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(54) **SEMICONDUCTOR AMOUNT-OF-DYNAMICS  
SENSOR AND MANUFACTURING METHOD  
THEREFOR**

(57) Abstract:

PROBLEM TO BE SOLVED: To provide a semiconductor amount-of-dynamics sensor for readily securing a closing property in a cap when protecting the movable part of beam structure with the cap.

SOLUTION: A sensor element part, consisting of a beam structure 2 as a movable part, fixed electrodes 9a-9c, and the like, is provided on the upper surface of a silicon substrate 17, an insulated and separated conductive thin film 19 is embedded between a sensor element part and the substrate 17, a wiring pattern and lower electrodes 22-25 formed by the conductive thin film 19 are electrically connected to electrode take-out parts 27a-27d arranged being nearly flush with the sensor element part, at the same time, a flat part 30 without steps so that the sensor element part is surrounded is formed between the electrode draw-out part on the substrate 17 and the sensor element, one surface side of a cap substrate 200

with a recessed part 202 at one surface side is joined to the flat part 30, and the sensor element part is covered with the recessed part 202 for protection.

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